

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q84452

Michel PUECH

Appln. No.: 10/516,455

Group Art Unit: 1792

Confirmation No.: 2876

Examiner: Allan W. OLSEN

Filed: December 3, 2004

For: METHOD AND DEVICE FOR SUBSTRATE ETCHING WITH VERY HIGH POWER
INDUCTIVELY COUPLED PLASMA

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one month, extending the time for responding to the Office Action of May 5, 2008 to September 5, 2008.

The statutory fee of \$120.00 is being charged to Deposit Account No. 19 4880 via EFS Payment Screen. The USPTO is also directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account.

Respectfully submitted,

/Dion R. Ferguson/

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Date: September 5, 2008